

Fig. 1A

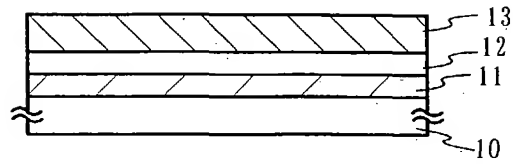


Fig. 1B

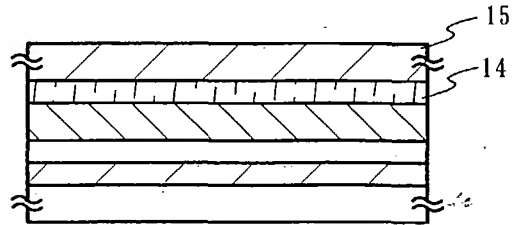


Fig. 1C

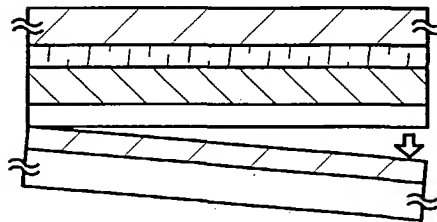


Fig. 1D

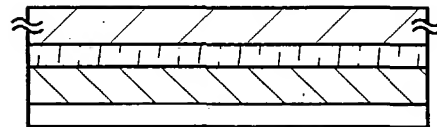


Fig. 1E

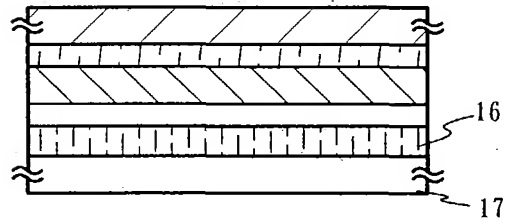


Fig. 1F

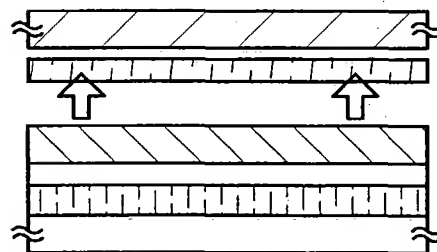
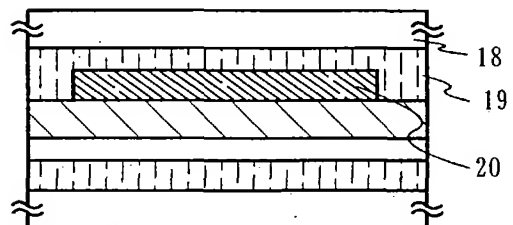


Fig. 1G



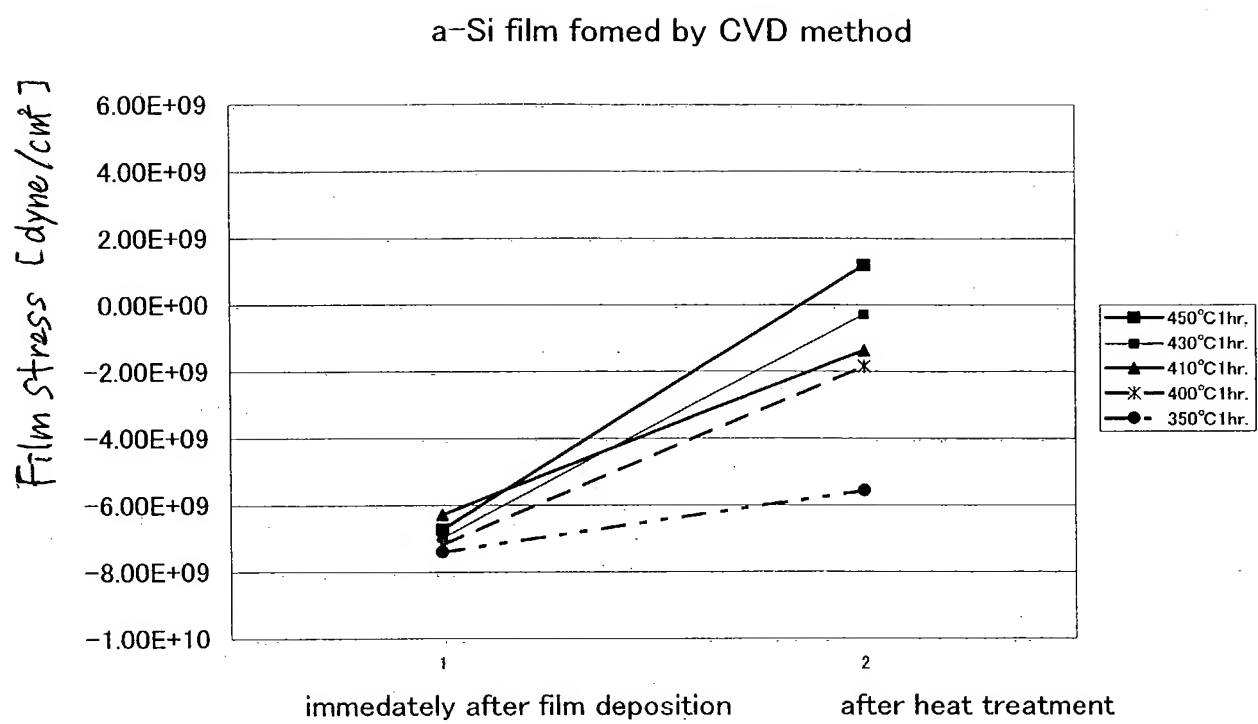


Fig. 2

Stress change of W(100nm)\SiO₂(100nm)

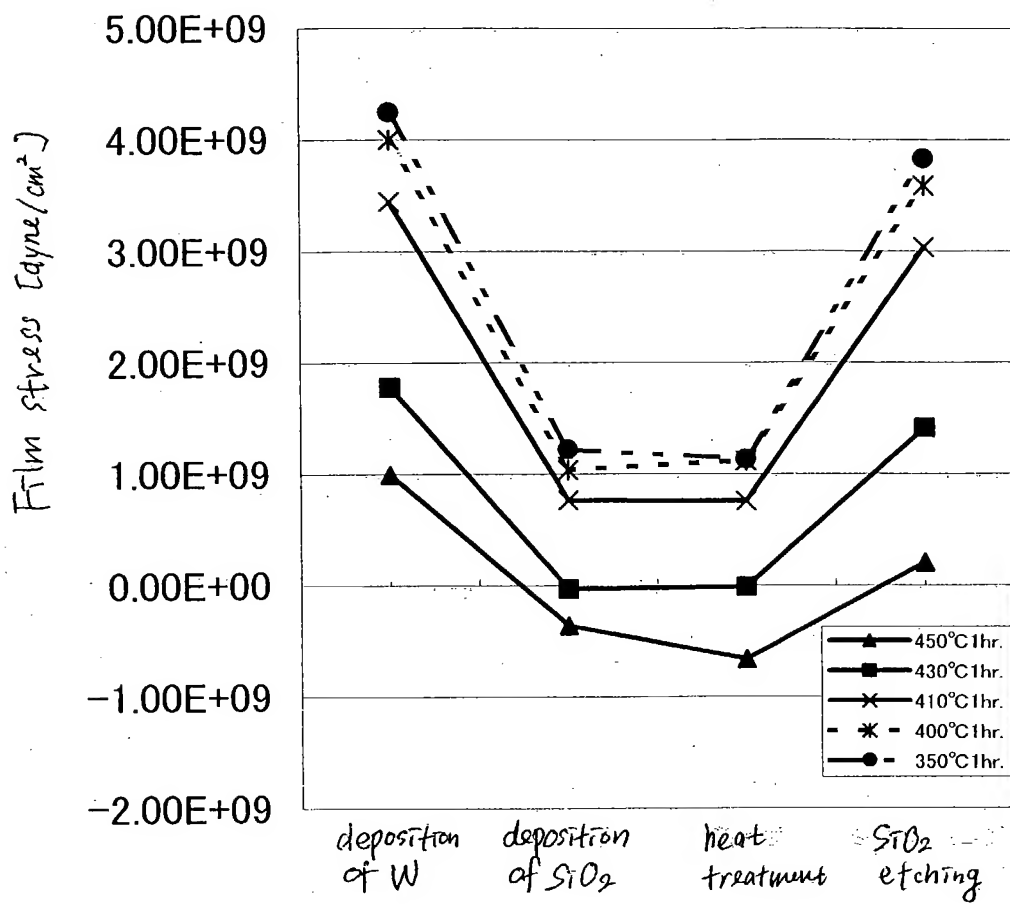


Fig. 3

Fig. 4A

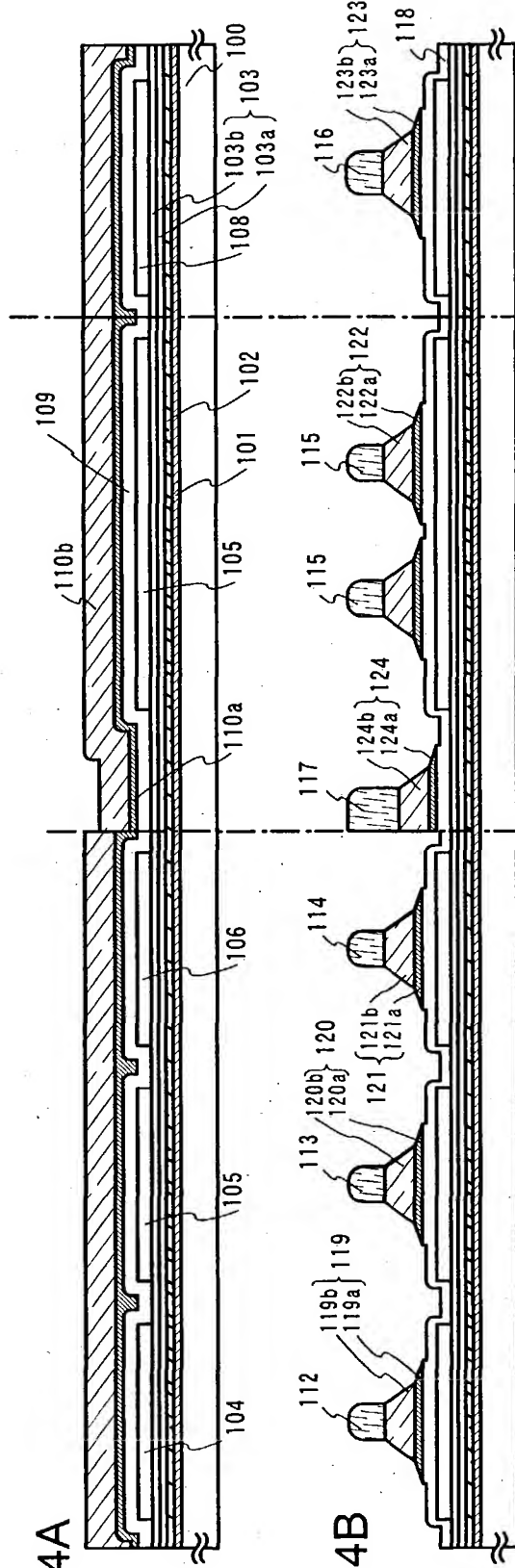


Fig. 4B

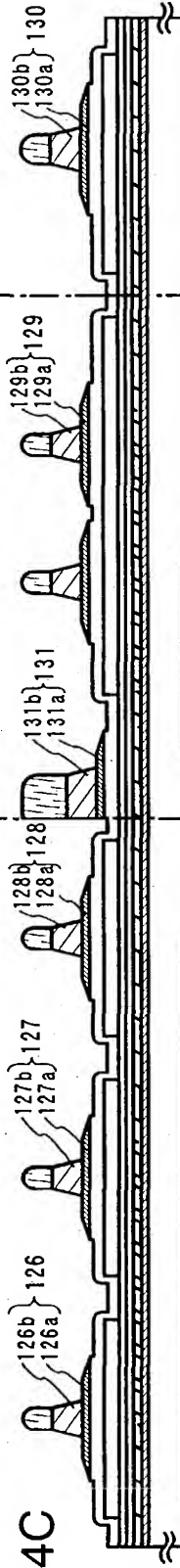


Fig. 4C

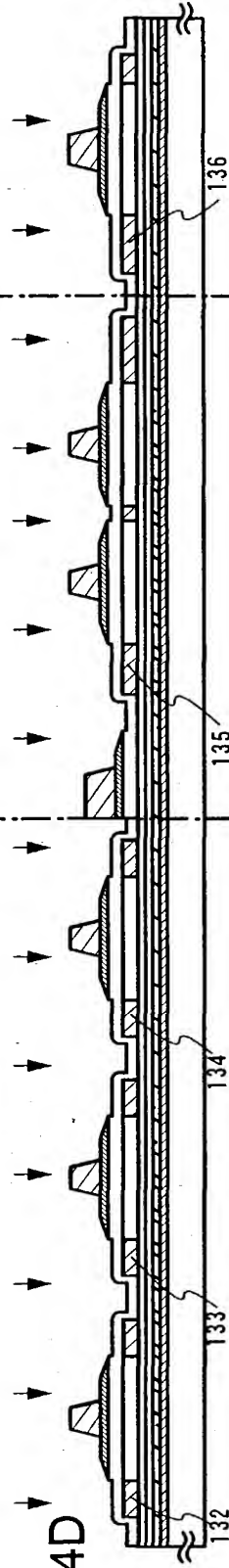


Fig. 4D

Fig. 5A

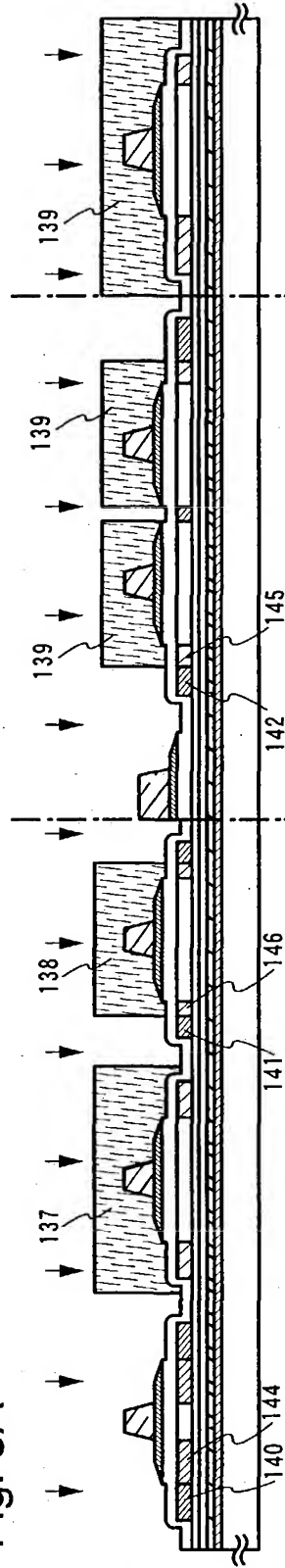


Fig. 5B

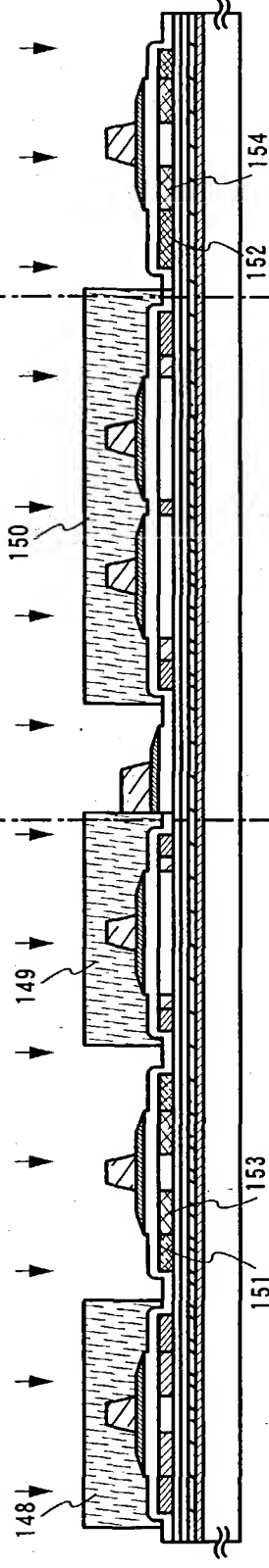
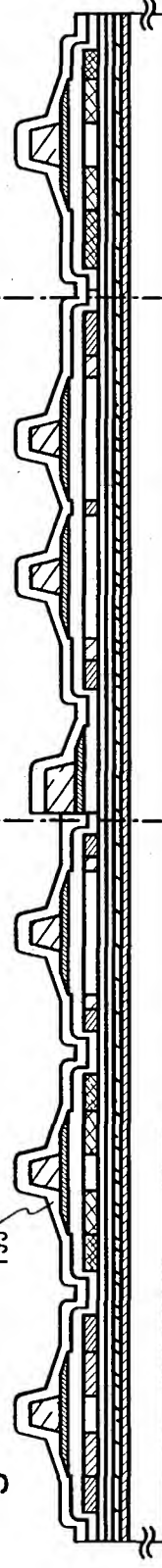


Fig. 5C



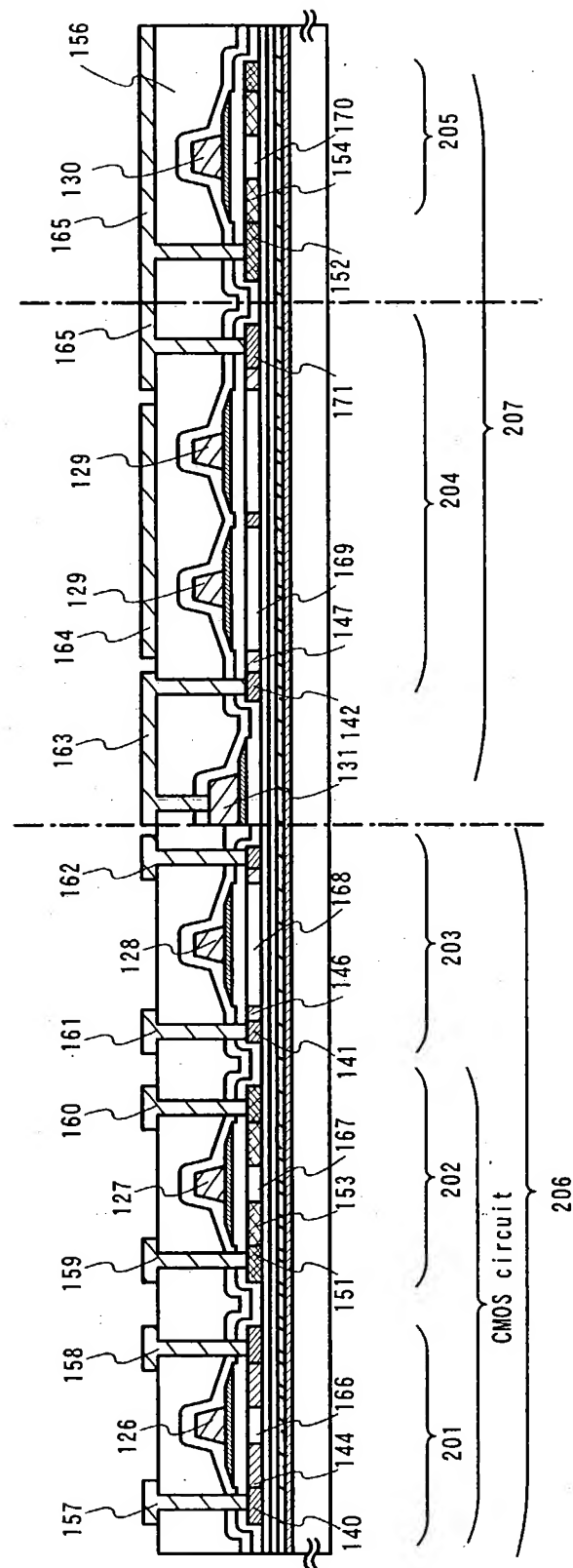


Fig. 6

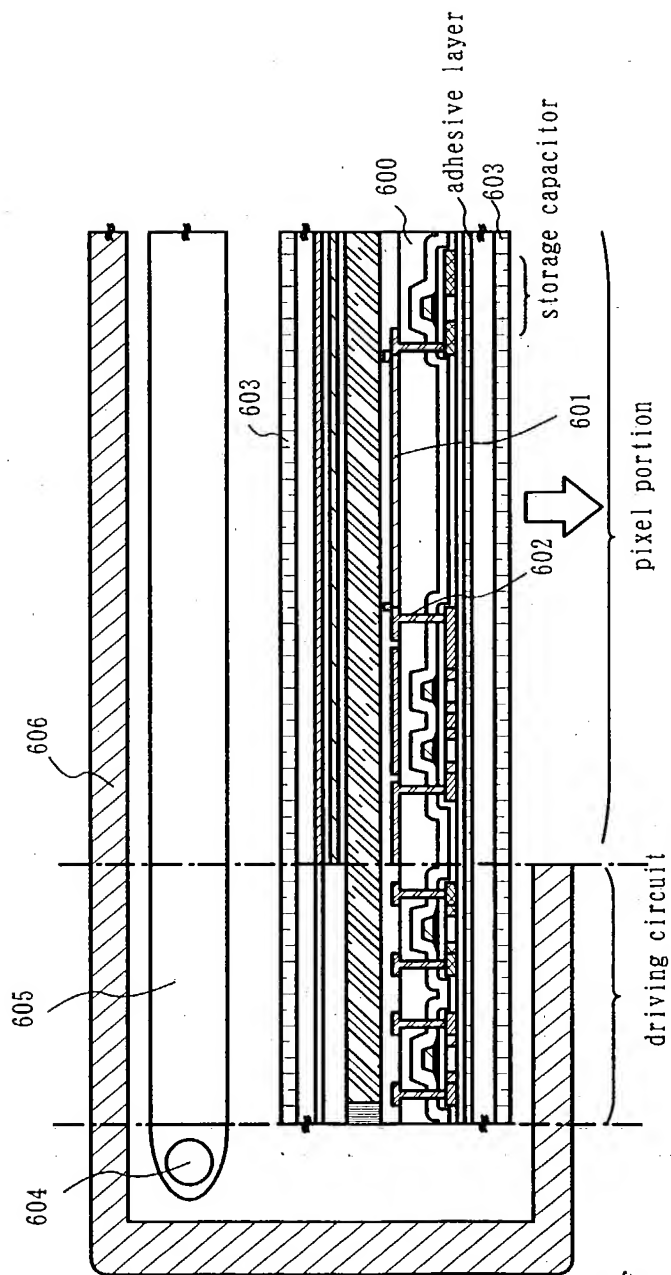


Fig. 7

Fig. 8A

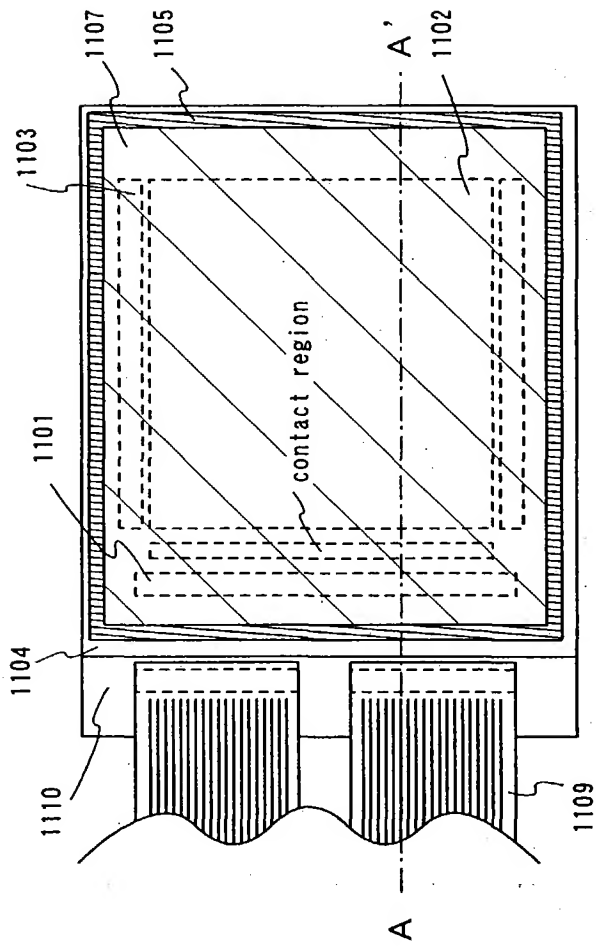


Fig. 8B

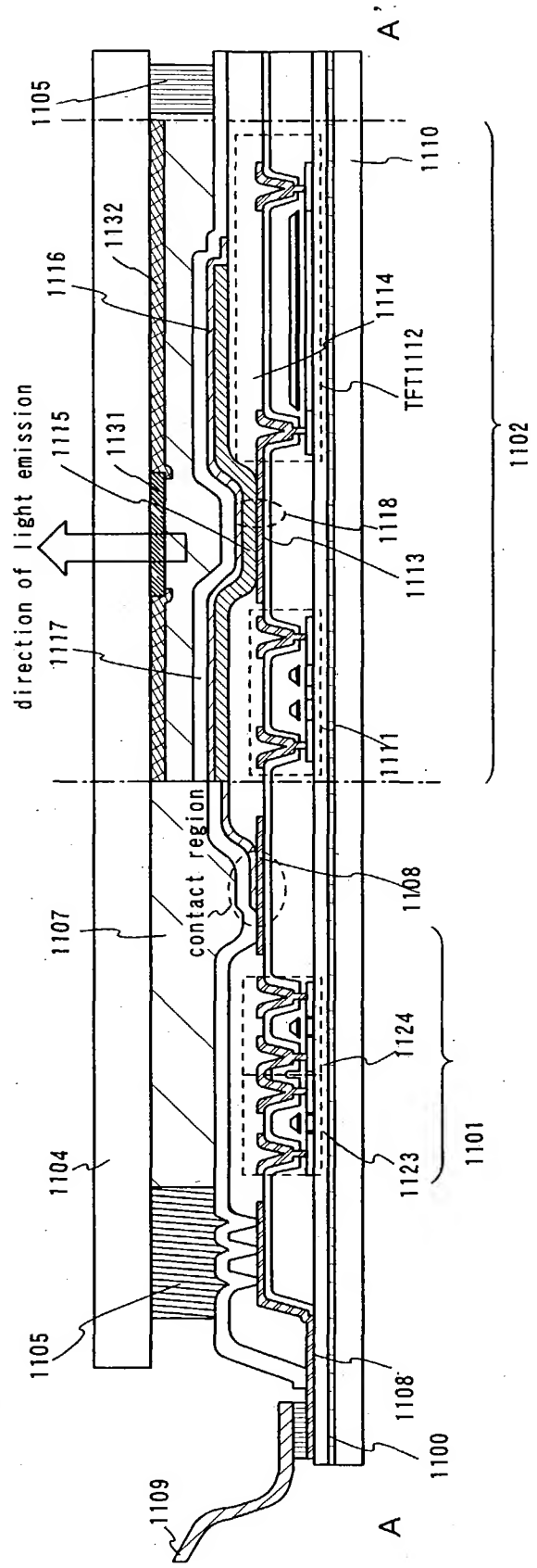


Fig. 9A

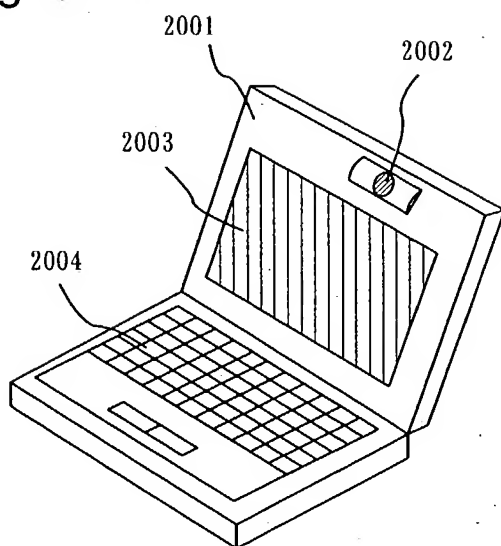


Fig. 9B

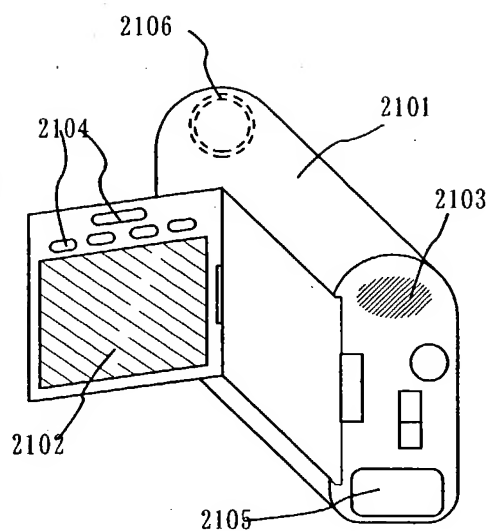


Fig. 9C

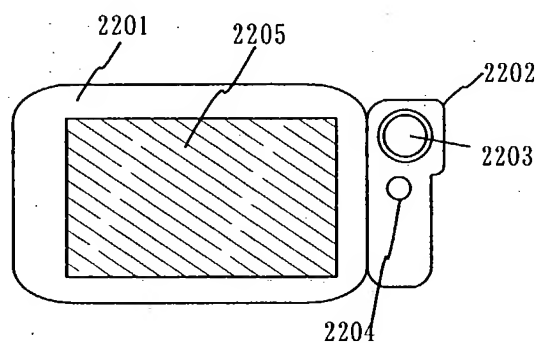


Fig. 9D

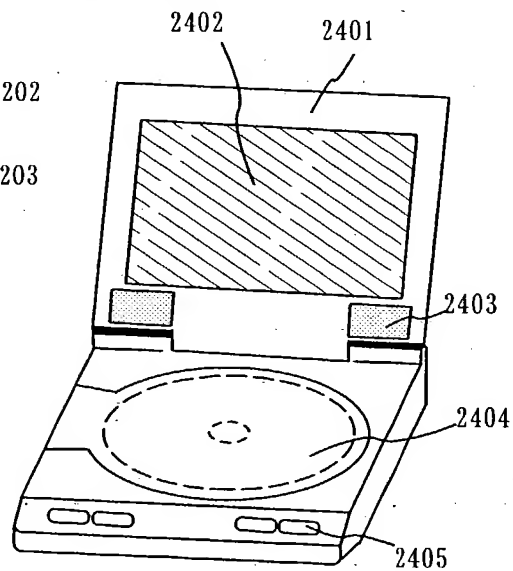


Fig. 9E

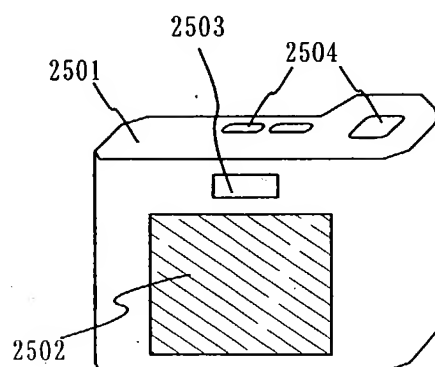


Fig. 10A

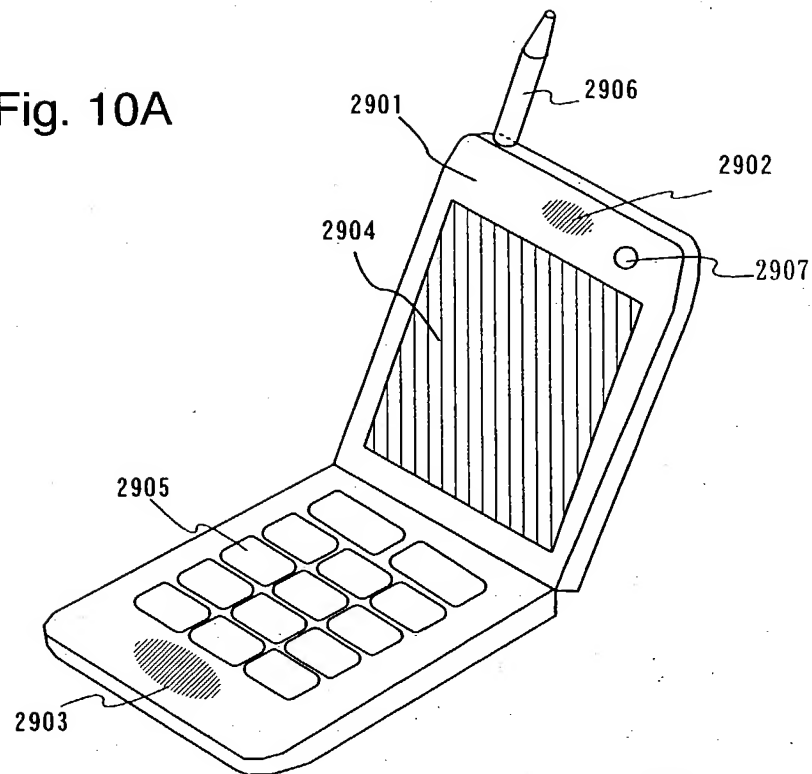


Fig. 10B

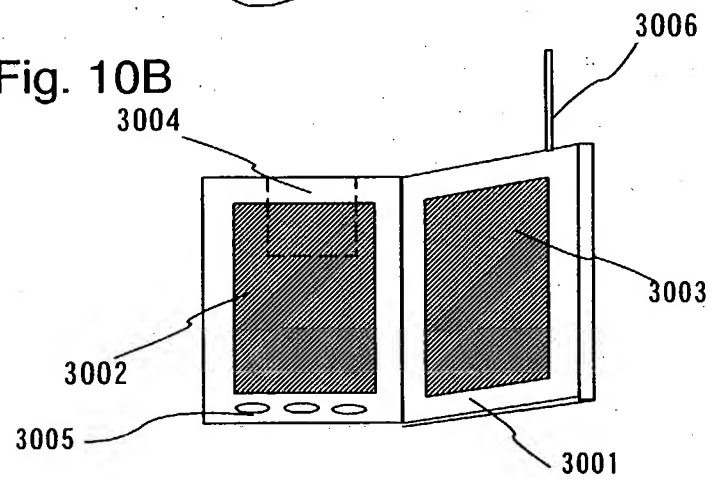


Fig. 10C

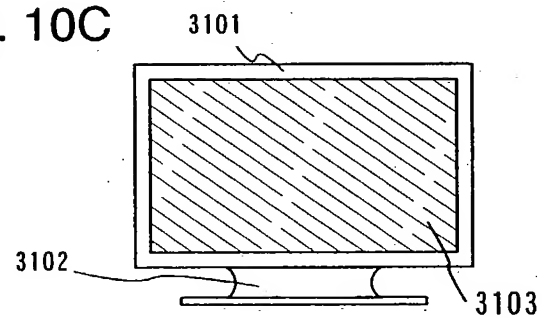


Fig. 11

